

United States Patent and Trademark Office

UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, Virginia 22313-1450 www.uspto.gov

| APPLICATION NO. | FILING DATE | FIRST NAMED INVENTOR | ATTORNEY DOCKET NO. | CONFIRMATION NO | |
|--|------------------|----------------------|-------------------------|-------------------------|--|
| 10/774,489 | 02/10/2004 | Hiroshi Sotozaki | 2004_0208 | 8916 | |
| 513 | 7590 03/24/2005 | | EXAMINER | | |
| WENDEROT 2033 K STREI | TH, LIND & PONAC | MACARTHUR, SYLVIA | | | |
| SUITE 800 WASHINGTON, DC 20006-1021 | | | ART UNIT | PAPER NUMBER | |
| | | | 1763 | | |
| | | | DATE MAILED, 02/24/2004 | DATE MAILED: 02/24/2005 | |

Please find below and/or attached an Office communication concerning this application or proceeding.

| Office Action Summary | | Application No. | Applicant(s) | | | | | |
|---|---|-------------------------------------|-----------------|--------|--|--|--|--|
| | | 10/774,489 | SOTOZAKI ET AL. | | | | | |
| | · · | Examiner | Art Unit | | | | | |
| | | Sylvia R MacArthur | 1763 | | | | | |
| | The MAILING DATE of this communication appe | ears on the cover sheet with the co | rrespondence ad | ldress | | | | |
| Period for Reply | | | | | | | | |
| A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.136 (a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely. - If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication. - Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). - Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b). Status | | | | | | | | |
| 1)[| Responsive to communication(s) filed on 10 F | ebruary 2004 . | • | | | | | |
| 2a)□ | | is action is non-final. | | | | | | |
| 3) | Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213. | | | | | | | |
| Dispositi | on of Claims | | | | | | | |
| 4)⊠ Claim(s) <u>1-21</u> is/are pending in the application. | | | | | | | | |
| | 4a) Of the above claim(s) is/are withdrawn from consideration. | | | | | | | |
| 5) Claim(s) is/are allowed. | | | | | | | | |
| 6)⊠ Claim(s) <u>1-21</u> is/are rejected. | | | | | | | | |
| · | | | | | | | | |
| _ | | | | | | | | |
| Application Papers | | | | | | | | |
| 9)☐ The specification is objected to by the Examiner. | | | | | | | | |
| 10) The drawing(s) filed on is/are objected to by the Examiner. | | | | | | | | |
| 11) The proposed drawing correction filed on is: a) □ approved b) □ disapproved. | | | | | | | | |
| 12) The oath or declaration is objected to by the Examiner. | | | | | | | | |
| Priority under 35 U.S.C. § 119 | | | | | | | | |
| 13)⊠ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). | | | | | | | | |
| a)⊠ All b)□ Some * c)□ None of: | | | | | | | | |
| | 1.⊠ Certified copies of the priority documents have been received. | | | | | | | |
| | Certified copies of the priority documents have been received in Application No | | | | | | | |
| | 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). | | | | | | | |
| * See the attached detailed Office action for a list of the certified copies not received. | | | | | | | | |
| 14) Acknowledgement is made of a claim for domestic priority under 35 U.S.C. § 119(e). | | | | | | | | |
| | | | | | | | | |
| Attachment(s) | | | | | | | | |
| Notice of References Cited (PTO-892) 18) Interview Summary (PTO-413) Paper No(s) Solition Notice of Draftsperson's Patent Drawing Review (PTO-948) 19) Notice of Informal Patent Application (PTO-152) 19 Other: 19 | | | | | | | | |
| Dotont and Tre | demail Office | | | | | | | |

Application/Control Number: 10/774,489 Page 2

Art Unit: 1763

cleaning unit (8a, 8b).

Claim Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 2. Claims 1-5, 7-12, 14-18, 20, and 21 have rejected under 35 U.S.C. 102(b) as being anticipated by Togawa (EP 0761387)

Regarding claims 1, 2, and 9: Togawa teaches a method of polishing and then cleaning a substrate. Claims 11 and 12 of Togawa cites that a parallel processing is performed is such that a workpiece is polished by a polishing unit and then a cleaning unit. The summary of the invention of Togawa lines 55-59 cites that the wafer is pressed against a polishing surface (cloth). The polishing apparatus comprising at least two polishing units/section (1a, 1b) and cleaning unit (7a,7b, 8a,8b). The cleaning units 7a, 7b (first cleaning units) and cleaning units/common second

Regarding claims 3, 10, and 16: According to the cleaning units 7a, 7b perform the same cleaning function see page 4, lines 47-49. The first cleaning unit cleans one substrate at a time as described in page 5 lines 41-52. Transfer robots 4a, 4b are used as conveyor to the substrate throughout the polishing apparatus.

Regarding claims 4, 11, and 17: Cleaning units 8a, 8b also serves as a drying unit, according page 4 lines 42-49.

Application/Control Number: 10/774,489 Page 3

Art Unit: 1763

Regarding claims 5, 7, 12, 14, 18, and 20: Togawa does cite in page 2 line 29 that the wafer is cleaned by water. Water is inherently an etching liquid. Water the universal solvent is surely capable of being used as an etchant and thus is inherently an etching liquid.

Regarding claims 8, 15, and 21:

Figures 1 and 5 illustrate that the first cleaning units

7a,b are arranged parallel to one another.

Note that according to Togowa if the polishing apparatus is not operated in the parallel processing, the polishing apparatus needs only three cleaning units.

Claim Rejections - 35 USC § 103

- 3. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 4. Claims 6, 13, and 19 are rejected under 35 U.S.C. 103(a) as being unpatentable over Togowa et al.

The teachings of Togowa were discussed above.

Togowa et al fails to specifically teach that the primary cleaning is performed in a longer time period than the secondary cleaning. However, the time duration that the cleaning operations are performed in the perspective cleaning units is an art recognizable parameter. The motivation to perform the primary cleaning at a longer time is that processing it in that fashion provides the desired product.

Conclusion

Application/Control Number: 10/774,489 Page 4

Art Unit: 1763

5. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Sylvia R MacArthur whose telephone number is 571-272-1438. The examiner can normally be reached on M-F during the core hours of 9 a.m. and 3 p.m..

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Parviz Hassanzadeh can be reached on 571-272-1435. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Sylvia R MacArthur Patent Examiner Art Unit 1763

March 16, 2005